

ABSTRACT OF THE DISCLOSURE

5 A method of manufacturing a miniature electromechanical
system (MEMS) device includes the steps of forming a moving
member on a first substrate such that a first sacrificial
layer is disposed between the moving member and the substrate,
encapsulating the moving member, including the first
10 sacrificial layer, with a second sacrificial layer, coating
the encapsulating second sacrificial layer with a first film
formed of a material that establishes an hermetic seal with
the substrate, and removing the first and second sacrificial
layers.

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